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G. Remnev, V. Tarbokov, S. Pavlov, F. Konusov, S. Zenkin, J. Musil

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#### ACCEPTED MANUSCRIPT

## Irradiation of sputtered Al-Si-N coatings by pulsed 200 keV C<sup>+</sup> ion beam

G. Remnev<sup>a\*</sup>, V. Tarbokov<sup>a</sup>, S. Pavlov<sup>a</sup>, F. Konusov<sup>a</sup>, S. Zenkin<sup>a</sup>, J. Musil<sup>a,b</sup>

<sup>a</sup>National Research Tomsk Polytechnic University, Lenin Avenue 30, 634050 Tomsk Russia

<sup>b</sup>Department of Physics and NTIS-European Centre of Excellence, University of West Bohemia,

Univerzitní 22, CZ-306 14 Plzeň, Czech Republic

\*E-mail: remnev06@mail.ru

#### **Abstract**

This paper reports on the effect of the irradiation of Al-Si-N coatings by an intense pulsed ion beam. The Al-Si-N coating was deposited on a steel substrate by a reactive magnetron sputtering. The Al-Si-N coating with a high silicon content (30 at.%) was irradiated by a high-intense pulsed C<sup>+</sup> ion beam. It was shown that metastable growth defects (GDs) created in the Al-Si-N coating during deposition can be healed up by its post-deposition irradiation using several pulses (1 and 10) of C<sup>+</sup> ions with energy E<sub>i</sub> = 200 keV, ion current density  $i_s = 7 \text{ A/cm}^2$ , pulse duration  $t_p = 110 \text{ ns}$  and radiation dose 2 MGy. The reduction in deposition-induced GD density results in an increased transmittance of the Al-Si-N coatings.

**Keywords:** Ion beam; Al-Si-N coating; Irradiation; Light transmittance; Magnetron sputtering.

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